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Application Number	10/646,533
Filing Date	August 22, 2003
First Named Inventor	Kenneth COLLINS, et al.
Art Unit	2813
Examiner Name	Jack S. Chen
Attorney Docket Number	006915 P02

## ENCLOSURES (Check all that apply)

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Remarks		

## SIGNATURE OF APPLICANT, ATTORNEY, OR AGENT

Firm Name	Law Office of Robert M. Wallace		
Signature			
Printed name	Robert M. Wallace		
Date	11-11-2005	Reg. No.	29,119

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I hereby certify that this correspondence is being facsimile transmitted to the USPTO or deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on the date shown below:

Signature			
Typed or printed name	Shelly Hart	Date	11-11-2005

This collection of information is required by 37 CFR 1.5. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.11 and 1.14. This collection is estimated to 2 hours to complete, including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, U.S. Department of Commerce, P.O. Box 1450, Alexandria, VA 22313-1450. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

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Date



PATENT

Attorney Docket No. 006915 P02

RW Ref. No. APM/001-02-CP1-1-2

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of  
Kenneth COLLINS, et al.

Entitled: PLASMA IMMERSION ION  
IMPLANTATION PROCESS USING A PLASMA  
SOURCE HAVING LOW DISSOCIATION AND  
LOW MINIMUM PLASMA VOLTAGE

Serial No.: 10/646,533

Filing Date: August 22, 2003

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)  
) Group Art Unit: 2813

)  
) Examiner: Jack S. Chen  
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)

INFORMATION DISCLOSURE STATEMENT UNDER 37 CFR 1.97(c) PRIOR TO  
FINAL ACTION AND WITHIN THREE MONTHS OF RECEIVING FOREIGN PATENT  
OFFICE COMMUNICATION

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Attached hereto is Form PTO-1449 listing documents believed relevant to the subject application. It is respectfully requested that these documents be made of record and an initialed copy of each form be returned to the undersigned.

I hereby certify that each item of information contained in this Information Disclosure Statement was cited in a communication (a copy of which is attached) from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of this statement.

It is believed that this disclosure complies with the requirements of 37 CFR 1.56 and the Manual of Patent Examining Procedures Section 707.5(b). If for some reason the Examiner considers otherwise, it is respectfully requested that the undersigned be called so that any deficiencies can be remedied.

A copy of each foreign patent document and/or non-patent

literature is enclosed. Some of the documents may have markings on them. No significance is meant to be attached to the markings. These documents are not necessarily analogous art.

Respectfully submitted,



Date:

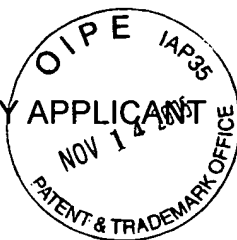
11/11/2005

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INFORMATION  
DISCLOSURE  
STATEMENT BY APPLICANT

Sheet 1 of 1



Application Number: 10/646,533  
Filing Date: August 22, 2003  
First Named Inventor: Kenneth COLLINS, et al.  
Group Art Unit: 2813  
Examiner Name: Jack S. Chen  
Attorney Docket Number: 006915 P02

**U. S. PATENT DOCUMENTS**

Examiner Initials	Document No	Publication Date	Name of Patentee or Applicant of Cited Document	Class	Subclass	Filing Date
	US-6,395,150 B1	05-28-2002	CAN CLEEMPUT ET AL.	204	192.37	04-01-1998
	US-6,413,321 B1	07-02-2002	KIM ET AL.	118	725	12-07-2000
	US 2003/0013260 A1	01-16-2003	GOSSMAN ET AL.	438	301	07-16-2001
	US 2003/0085205 A1	05-08-2003	LAI ET AL.	219	121.43	04-20-2001

**FOREIGN PATENT DOCUMENTS**

Examiner Initials	Foreign Patent Document	Publication Date	Country	Name of Patentee or Applicant of Cited Document	Translation? (Yes/No/n/a)
	EP 1 158 071 A2	28.11.2001	EUROPE	APPLIED MATERIALS, INC.	N/A
	JP 070455542	14.02.1995	JAPAN	MATSUSHITA ELECTRIC IND CO LTD	N/A
	JP 2000150908	30.05.2000	JAPAN	SEMICONDUCTOR ENERGY LAB CO LTD	N/A

**NON PATENT LITERATURE DOCUMENTS**

Examiner Initials	
	Hu, C.-K., et al., "A process for improved Al(cu) reactive ion etching", Journal of Vacuum Science and Technology", May 1, 1989, pp. 682-685, Vol. 7, No. 3, American Institute of Physics, New York, U.S.

Examiner's Signature:

Date Considered:

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.